

open front at an insertion level and lowered to sit on the upwardly extending beads at the seating level.

(1) 7. The wafer carrier of claim ⁶, wherein each shelf is further comprised of a forward stop positioned at the seating level at least partially forward and inwardly of the upwardly extending beads thereby interfering with the forward movement of a wafer seated in said shelf, each shelf further having a rearward stop positioned rearwardly and inwardly of the upwardly extending beads thereby interfering with the rearward movement of a wafer in said shelf, said forward stop not extending into the insertion level whereby the wafer may be inserted and removed at the insertion level without interference with said forward stop.

(5) 8. The wafer carrier of claim ⁶ further comprising a molded outer transparent shell extending around and enclosing the left side, the backside and the right side and further comprising a door for closing the open front.

(1) 9. The wafer carrier of claim ⁸ wherein each column of wafer support shelves are formed separately from the outer shell and wherein the columns are attached to the outer shell.

(5) 10. The wafer carrier of claim ⁸ wherein each column of shelves is separately formed from the outer shell and each column is formed of a static dissipative material,

wherein the carrier further comprises a plurality of parts formed of static dissipative plastic material, wherein said parts are conductively connected by way of static dissipative plastic.

(6) 11. The wafer carrier of claim ¹⁰ wherein the static dissipative plastic is configured as at least one jumper extending from one part to another part.

(1) 12. The wafer carrier of claim ¹⁰ wherein said parts include a robotic flange, a side handle, and a bottom base portion having an equipment interface said bottom base portion separately

formed from the outer shell and formed of a static dissipative plastic material, said robotic flange separately formed from the outer shell and formed of a static dissipative plastic material

(8) 13. The wafer carrier of claim 1⁷ wherein the bottom base portion comprises a kinematic coupling.

(9) 14. A wafer carrier for holding wafers, the wafer carrier having an open front, an open interior, a closed backside, a top portion, a bottom base portion, a closed left side, a closed right side, a pair of wafer supports positioned in the open interior, a pair of side wall handles and a robotic flange at the top portion the carrier, the robotic flange, the side wall handles, the wafer supports, and the bottom base portion all formed of static dissipative plastic and conductively connected together.

(10) 15. The wafer carrier of claim 1⁴ further comprising a conductive plastic jumper.

(11) 16. The wafer carrier of claim 1⁵ wherein the conductive plastic jumper is fixed in the interior of the wafer carrier.

(12) 17. The wafer carrier of claim 1⁵ wherein the conductive plastic jumper is connected to one of the side wall handles.

(13) 18. A wafer carrier for holding wafers, the wafer carrier having an open front, an open interior, a nonconductive plastic shell, a top, a bottom base portion, a closed left side, a closed right side, a pair of wafer supports positioned in the open interior, a pair of side wall handles attached to the nonconductive plastic shell, a robotic flange at the top, the robotic flange, the side wall handles, the wafer supports, and the bottom base portion all formed of static dissipative plastic and conductively connected together.

(14) 19. The wafer carrier of claim 1⁸ further comprising a kinematic coupling on the bottom base portion.

(b) 20. The wafer carrier of claim 18 further comprising a conductive plastic jumper providing a conductive connection.

(b) 21. The wafer carrier of claim 18 wherein the plastic shell is transparent.

[Please add new claims 22 as follows:

(b) 22. (New) A wafer carrier for holding a plurality of wafers in an axially aligned stacked arrangement, the carrier comprising:

a container portion having a left side, a right side, an open front and an open interior for receiving and holding the wafers, the container portion having a plurality of shelves at the right side in the interior and a plurality of shelves at the left side in the interior, each shelf having a pair of upwardly extending protrusions for supporting the wafers, at least one of the protrusions on each shelf comprising an elongate bead oriented inwardly; and

a door for closing the open front.

REMARKS

With respect to the Double Patenting rejection, attached please find a Terminal Disclaimer which it is believed obviate said objection.

In view of the foregoing, it is submitted that this application is in condition for allowance. Favorable consideration and prompt allowance of the application are respectfully requested.

The Examiner is invited to telephone the undersigned if the Examiner believes it would be useful to advance prosecution.

Respectfully submitted,


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